# Thermal Transport in Layered Materials, Devices, and Systems

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#### Outline

- Energy problems in electronics
- 2D materials for 3D integration
- Fundamental thermal properties of 2D materials
- Devices & systems with 2D and layered materials
- Acknowledgements

![](_page_3_Picture_1.jpeg)

Cooking Pancake on AMD CPU!! CPUでホットケーキを作ってみた!

27,705 views • Mar 14, 2020

1 924 **●** 35 SHARE =+ SAVE ...

![](_page_4_Picture_1.jpeg)

These are the most cringe-worthy chat up lines submitted and voted for by Brits on Thortful.com, with "You are hotter than the bottom of my laptop" taking the top spot as the cheesiest of them all.

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E. Pop, *Nano Research* 3, 147 (2010) Energy in Electronics, EE 323

![](_page_5_Figure_2.jpeg)

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#### **Excess Heat = High Cooling Costs**

![](_page_6_Picture_2.jpeg)

![](_page_7_Figure_1.jpeg)

Figure by Alex Gabourie (Pop Lab). Original data collected by M. Horowitz, F. Labonte, O. Shacham, K. Olukotun, L. Hammond, and C. Batten. Data from 2010 through 2019 collected by K. Rupp.

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#### Moore's Law vs. Dennard's Law

# Cramming more components onto integrated circuits

With unit cost falling as the number of components per circuit rises, by 1975 economics may dictate squeezing as many as 65,000 components on a single silicon chip

![](_page_8_Picture_3.jpeg)

Director, Research and Development Laboratories, Fairchild Semiconductor division of Fairchild Camera and Instrument Corp.

![](_page_8_Figure_5.jpeg)

250

IEEE JOURNAL OF SOLID-STATE CIRCUITS, VOL. SC-9, NO. 5, OCTOBER 1974

#### Design of Ion-Implanted MOSFET's with Very Small Physical Dimensions

ROBERT H. DENNARD, MEMBER, 1EEE, FRITZ H. GAENSSLEN, HWA-NIEN YU, MEMBER, 1EEE, V. LEO RIDEOUT, MEMBER, 1EEE, ERNEST BASSOUS, AND ANDRE R. LEBLANC, MEMBER, 1EEE

Device or Circuit Parameter	Scaling Factor
Device dimension $t_{ox}$ , L, W	1/κ
Doping concentration $N_a$	κ
Voltage V	$1/\kappa$
Current I	1/ĸ
Capacitance $\epsilon A/t$	$1/\kappa$
Delay time/circuit VC/I	1/8
Power dissipation/circuit VI	$1/\kappa^2$
Power density $VI/A$	1

![](_page_8_Picture_11.jpeg)

![](_page_8_Figure_12.jpeg)

#### Moore: complexity vs. cost not ending, going 3D...

#### **Dennard: geometric scaling**

~ ending at atom-scale

# The Problem with Computing Today

M. Aly, [...], K. Goodson, C. Kozyrakis, E. Pop, J. Rabaey, C. Re, H.-S.P. Wong, S. Mitra, IEEE Computer (2015)

![](_page_9_Figure_2.jpeg)

**Future:** 3D integrated logic <u>and</u> memory 10 to 1000x more energy-efficient

#### **3D Is Driving our 2D and Thermal Work**

- Can some new materials replace silicon in 3D?
- Short answer: NOT replace, BUT complement 3D heterogeneous integration

![](_page_10_Figure_3.jpeg)

![](_page_10_Picture_4.jpeg)

#### **32-layer vertical Flash memory**

- Silicon-CMOS compatibility is required
- For back-end of the line (BEOL) this usually means < 500 °C for < 2 hours</li>

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#### Historical Sidenote: 3D at Stanford in 1982

![](_page_11_Picture_1.jpeg)

- 3D "high-rise" electronics pursued at least since early 1980s
- Why didn't this work?
  - Laser-crystallized amorphous silicon
  - Silicon scaled just fine below 1 μm

![](_page_11_Picture_6.jpeg)

on research in 3-D technology: Semiconductor engineers may soon leave their two-dimensional confines and build three-dimensional semiconductor chips. These 3-D chips hold the promise of significantly increasing the speed and capability of future computers. The basic techniques needed to produce these chips, known as "high-rise" technology, were developed by Jim Gibbons and his students in the Solid-State Laboratory.

September 1982 \* CIS Newsletter \* Stanford University

# In 3D, Thermal Properties Are Very Important

![](_page_12_Figure_1.jpeg)

- **High power density** → FEOL cooking BEOL, logic cooking memory, ...
- 3D integration → many **interfaces** and (usually) **low-***K*<sup>\*</sup> dielectrics
- Performance  $(I_{on})$  degrades with  $\uparrow T$ ... leakage  $(I_{off})$  and reliability  $\sim exp(T)$

\*Low-k (permittivity) and low- $\kappa$  (thermal conductivity)

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### What Are 2-Dimensional (2D) Materials?

![](_page_14_Figure_1.jpeg)

- One-to-three atom thick materials... metals, insulators, semiconductors
- Practical band gaps (~2 eV) + electron & hole mobilities ~ 100 cm<sup>2</sup>V<sup>-1</sup>s<sup>-1</sup> in atomically thin semiconductors, better than silicon in sub-1 nm thin films
- Van der Waals bonds → heterogeneous integration w/out lattice matching (possible at low-temperature)

## Ex: Electron & Phonon Bands of 2D MoS<sub>2</sub>

![](_page_15_Figure_1.jpeg)

![](_page_15_Figure_2.jpeg)

#### Huge Advances in 2D Synthesis

![](_page_16_Figure_1.jpeg)

-2

-3

### **Thermal Properties of 2D Materials**

![](_page_17_Figure_1.jpeg)

- Huge thermal anisotropy of 2D materials: in-plane  $\kappa_{||} >>$  cross-plane  $\kappa_{\perp}$
- Can thermal anisotropy be leveraged for heat blocking and spreading?
- Thermal properties must be understood in both 3D systems and devices

# Thermal κ of MoS<sub>2</sub> on SiO<sub>2</sub> Decreases

A. Gabourie, S. Suryavanshi, A.B. Farimani, E. Pop, 2D Materials, 8, 011001 (2021)

![](_page_18_Figure_2.jpeg)

- Suspended, isolated  $MoS_2$  thermal  $\kappa$  is comparable to  $\kappa$  of doped silicon
- SiO<sub>2</sub>-supported or encased MoS<sub>2</sub> thermal κ decreases 50 to 80%
- Why? Scattering with **remote phonons** (but less for bilayers)
- This is important for sub-150 nm transistors (heat flow to contacts)

# Thermal κ of MoS<sub>2</sub> on Other Substrates

A. Gabourie, Ç. Köroğlu, E. Pop, J. Appl. Phys. 131, 195103 (2022)

![](_page_19_Figure_2.jpeg)

- Thermal κ of MoS<sub>2</sub> best preserved on c-AIN, c-AI<sub>2</sub>O<sub>3</sub>, or h-BN
- Why? Long-wavelength vibrational density of states (< 2 THz)</li>
- Thermal boundary conductance (TBC) scales differently → tuning?

## Cross-Plane Thermal κ<sub>z</sub> of MoS<sub>2</sub>

A. Sood, F. Xiong, S. Chen, [...], D. Donadio, K. Goodson, E. Pop, Nano Lett. 19, 2434 (2019)

![](_page_20_Figure_2.jpeg)

- Cross-plane thermal κ<sub>z</sub> scales with thickness, t (ballistic to diffusive)
- Phonon mean free paths MFP > 200 nm carry ~50% of the heat

# Cross-Plane Thermal κ<sub>z</sub> of MoS<sub>2</sub>

A. Sood, F. Xiong, S. Chen, [...], D. Donadio, K. Goodson, E. Pop, *Nano Lett.* **19**, 2434 (2019) A. Sood, C. Sievers, [...], D. Donadio, K. Goodson, E. Pop, *ACS Nano* **15**, 19503 (2021)

![](_page_21_Figure_2.jpeg)

- Cross-plane thermal κ<sub>z</sub> scales with thickness, t (ballistic to diffusive)
- Phonon mean free paths MFP > 200 nm carry ~50% of the heat
- Thermal κ<sub>z</sub> lower for Graphene-MoS<sub>2</sub> superlattices (e.g. GMGMG)

#### Outline

- Energy problems in electronics
- 2D materials for 3D integration
- Fundamental thermal properties of 2D materials
- Devices & systems with 2D and layered materials
- Acknowledgements

### Wanted: 2D Transistors for 3D Integration

C. English, K. Smithe, R.L. Xu, E. Pop, IEDM (2016)

A. Daus, S. Vaziri, [...], E. Pop, *Nature Elec.* **4**, 495 (2021)

![](_page_23_Figure_3.jpeg)

![](_page_23_Figure_4.jpeg)

- 10 nm-scale MoS<sub>2</sub> transistors on rigid SiO<sub>2</sub>/silicon
- Then-record I<sub>D</sub> ≈ 400 µA/µm

- 100 nm-scale MoS<sub>2</sub> transistors on flexible polyimide (PI)
- Record  $I_{\rm D} \approx 300$  to 470 µA/µm
- Limited by contact resistance (R<sub>c</sub>), gate stack, and self-heating

## Energy Dissipation in MoS<sub>2</sub> Transistors

E. Yalon, C. McClellan, K. Smithe, R.L. Xu, M. Munoz Rojo, S. Suryavanshi [...] E. Pop, *Nano Letters* **17**, 3429 (2017) E. Yalon, Ö.B. Aslan, K. Smithe, C. McClellan, S. Suryavanshi, [...], E. Pop, *ACS Appl. Mater. Interfaces* **9**, 43013 (2017)

![](_page_24_Figure_2.jpeg)

![](_page_24_Figure_3.jpeg)

- First measurement of power dissipation in large MoS<sub>2</sub> transistors (Raman and SThM)
- They get hot (>200°C) during operation!
- Why? Poor **thermal boundary conductance** (TBC) of MoS<sub>2</sub>-SiO<sub>2</sub> van der Waals interface

![](_page_24_Figure_7.jpeg)

work of Alex Gabourie

### Where Does the Heat Go in Transistors?

A. Gabourie, Ç. Köroğlu, E. Pop, J. Appl. Phys. 131, 195103 (2022)

![](_page_25_Figure_2.jpeg)

#### Back-gated 2D transistors:

- L > 150 nm, heat flows to substrate
- L < 150 nm, heat flows **to contacts**

A. Daus, S. Vaziri, [...], E. Pop, Nature Elec. 4, 495 (2021)

![](_page_25_Figure_7.jpeg)

#### Dual-gated transistors or on plastics:

- It's complicated
- Ex: heat flow into gate, then contacts

## **Can Pulsing Eliminate Self-Heating?**

K. Smithe, C. English, S. Suryavanshi, E. Pop, *Nano Letters* **18**, 4516 (2018) J. Nathawat, K. Smithe, C. English, [...], E. Pop, J. Bird, *Phys. Rev. Mater.* **4**, 014002 (2020)

![](_page_26_Figure_2.jpeg)

- High current in  $MoS_2 \rightarrow$  Joule heating limits saturation velocity  $v_{sat}$  and  $I_D$
- Ultra-fast pulsed measurements (< 4 ns) below thermal and (most) charge trapping time constants reduce self-heating
- $v_{sat}$  from 3.4 x 10<sup>6</sup> cm/s to 6 x 10<sup>6</sup> cm/s  $\rightarrow$   $I_D$  can be ~ 1 mA/µm (with  $n \sim 10^{13}$  cm<sup>-2</sup>)

### Very Large Cross-Plane Thermal Resistance

S. Vaziri, E. Yalon, M. Munoz Rojo, S. Suryavanshi, C. McClellan, [...] E. Pop, Science Adv. 5, eaax1325 (2019)

![](_page_27_Figure_2.jpeg)

### **Unusual Application: Thermal Transistor #1**

A. Sood, F. Xiong, [...], D. Donadio, Y. Cui, E. Pop, K Goodson, Nature. Comm. 9, 4510 (2018)

- Use reversible Li intercalation in MoS<sub>2</sub>
- Switch heat flow by ~10x as a thermal transistor  $\rightarrow$  control T transients

![](_page_28_Figure_4.jpeg)

### **Unusual Application: Thermal Transistor #2**

M.E. Chen, M. Muñoz Rojo, F. Lian, J. Koeln, [...], A.G. Alleyne, K.E. Goodson, E. Pop, 2D Materials 8, 035055 (2021)

- Use switching of **suspended graphene membrane**
- Much faster thermal switch (~ns) but lower thermal on/off ratio

![](_page_29_Figure_4.jpeg)

## **Applications to Phase-Change Memory**

F. Xiong, A.D. Liao, D. Estrada, E. Pop, Science 332, 568 (2011)

- Chalcogenides e.g. Ge<sub>2</sub>Sb<sub>2</sub>Te<sub>5</sub> (GST)
- Large resistance change (HRS/LRS)
- Multi-levels for neuromorphic applications

![](_page_30_Picture_5.jpeg)

HRS

amorphous

• Reversible phase change induced by Joule heating (pulsed V or I)

![](_page_30_Figure_7.jpeg)

\*HRS, LRS = high, low resistance state

LRS\*

crystalline

>>

# Exploiting Graphene, MoS<sub>2</sub> As Thermal Barrier

C. Ahn, S. Fong, Y. Kim, S. Lee, A. Sood, C. Neumann, K. Goodson, E. Pop, H.-S.P. Wong, *Nano Lett.* **15**, 6809 (2015) C. Neumann, K. Okabe, E. Yalon, R. Grady, H.-S.P. Wong, E. Pop, *Appl. Phys. Lett.* **114**, 082103 (2019)

![](_page_31_Figure_2.jpeg)

Phase-change memory (PCM)

![](_page_31_Figure_3.jpeg)

- Exploiting 2D cross-plane thermal boundary resistance (TBR)
- Ultrathin thermal barrier limits PCM heat loss  $\rightarrow$  lower switching power

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# Layered Superlattice Phase-Change Memory

![](_page_32_Figure_1.jpeg)

- If one thermal barrier is good, how about a **superlattice** of them?
- $Sb_2Te_3/GeTe$  superlattices  $\rightarrow$  from wave-like to particle-like heat flow
- Superlattice PCM on flexible plastic substrates with ultralow current
  → also assisted by low thermal conductivity substrate

#### **Thermal Challenges in 3D Systems**

Ç. Köroğlu, E. Pop, IEEE Electron Device Lett. 44, 496 (2023)

![](_page_33_Figure_2.jpeg)

- High power density in 3D → different layers are cooking each other
- 3D integration has many interfaces and (usually) low-K\* dielectrics
- We looked at AIN (iso) and hBN (anisotropic) as heat spreaders in 3D ICs

#### **Thermal Measurements in Our Group**

#### **Raman thermometry**

![](_page_34_Figure_2.jpeg)

#### Scanning Thermal Microscopy (SThM)

![](_page_34_Figure_4.jpeg)

S. Deshmukh et al., Science Adv. 8, eabk1514 (2022)

S. Vaziri et al. *Sci. Adv.* **5**, eaax1325 (2019)

• Raman thermometry → material-specific,

~0.5 µm spatial resolution, sub-1 nm vertical resolution

 Scanning Thermal Microscopy (SThM) → surface temperature, ~50 nm resolution

![](_page_34_Picture_10.jpeg)

S. Bohaichuk, *Nano Lett.* (2019) neuron-like spiking

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- Moore's Law is not dead, it's going 3D
- VdW interfaces  $\rightarrow$  2D semiconductors are good for 3D integration
- But, also: VdW interfaces → weak thermal coupling (sometimes we can leverage these, other times they are headaches)
- **3D integrated systems** have thermal challenges
- Nanoscale thermal measurements are key
- Electro-thermal **co-design** is important

![](_page_35_Picture_7.jpeg)

### Acknowledgements

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#### • Alumni:

- Prof. D. Estrada, F. Xiong, S. Islam, E. Yalon, M. Muñoz Rojo, K. Brenner, A. Sood, A. Daus
- Dr. A. Behnam, M.-H. Bae, Z.-Y. Ong, A. Liao, Z. Li, V. Dorgan, E. Carrion, N. Wang, K. Grosse
- Dr. C. English, F. Lian, K. Smithe, S. Suryavanshi, S. Vaziri, S. Deshmukh, M. Mleczko, C. Neumann
- Dr. R.L. Xu, S. Bohaichuk, I. Datye, A. Gabourie, C. McClellan, V. Chen, M. Chen, C. Bailey

#### • Current Group:

- Dr. K. Nassiri Nazif, T. Pena, A. Persson, A.T. Hoang
- J.-S. Ko, Ç. Köroğlu, A.I. Khan, K. Neilson, M. Islam, S. Wahid, M. Jaikissoon
- C. Nattoo, J. Yang, M. Wang, R. Bennett, L. Hoang, X. Wu, C. Cremers, H. Su

#### • Undergrads:

- Vivian, Kamila, Neel, Noor, Sidra, Maisy, Paul, Bozo, Megan, Stephone, Anika, Aria, Erin
- Priyanka, Peter, Justin, Job, Tim, Andrew, Yeshar, Juan-Pablo, Jayan, Akshay, ++
- Sponsors:
  - SRC-DARPA JUMP, NSF, SystemX, NMTRI, Micron, Samsung, Intel, TSMC
- Collaborators (incomplete list):
  - Z. Bao, M. Brongersma, W. Cai, Y. Cui, R. Dauskardt, I. Fisher, D. Goldhaber-Gordon, K. Goodson, T. Heinz, R. Howe, A. Lindenberg, N. Melosh, S. Mitra, Y. Nishi, K. Olukotun, P. Pianetta, E. Reed, A. Salleo, K. Saraswat, D. Senesky, Z.X. Shen, M.F. Toney, H.-S.P. Wong, X. Zheng (Stanford)
  - A. Alleyne, D. Cahill, M. Gilbert (UIUC), D. Donadio (UC Davis), D. Jena, G. Xing (Cornell), A. Franklin (Duke), S. Das, S. Mohney (PSU), I. Takeuchi (UMD), T. Grasser (TU Wien), D. Ielmini, R. Sordan (Milano), A. Majumdar (UW), R. Wallace (UTD), S. Datta (GATech), A. Newaz (SFSU), S. Koester (UMN), C. Richter (NIST), K. O'Brien, I. Karpov (Intel)

![](_page_36_Picture_19.jpeg)

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